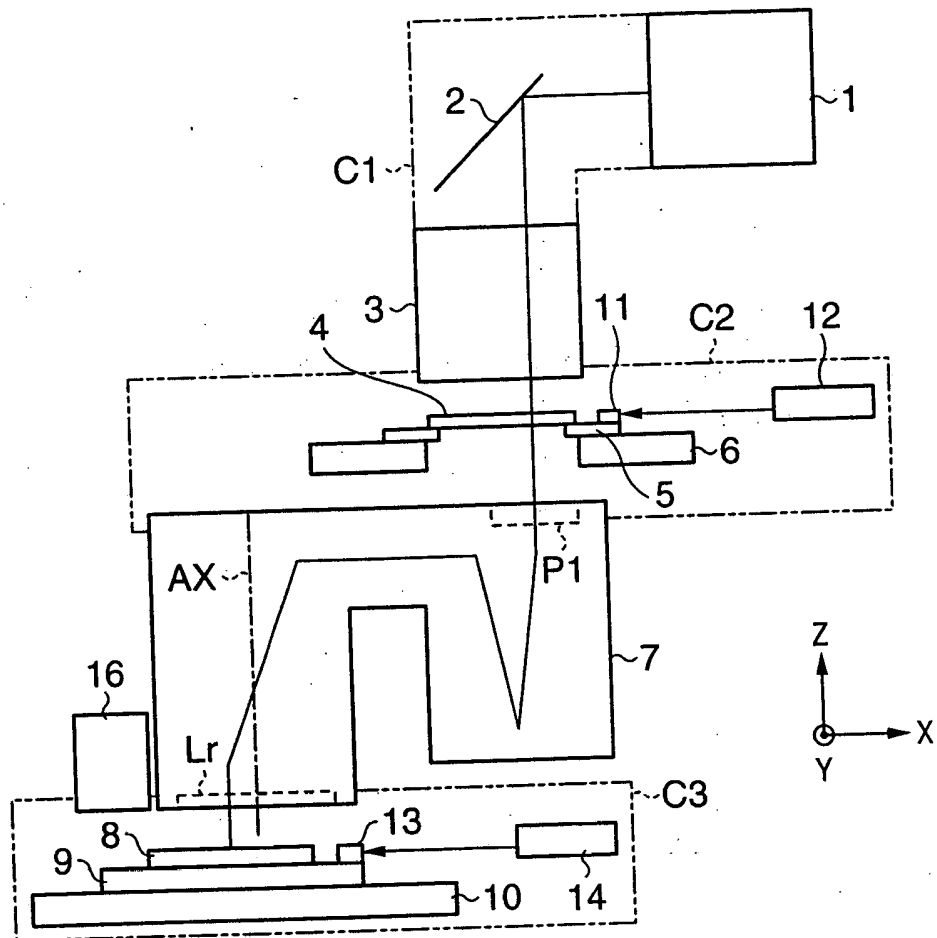


FIG. 1



00000000-11100

FIG. 2A

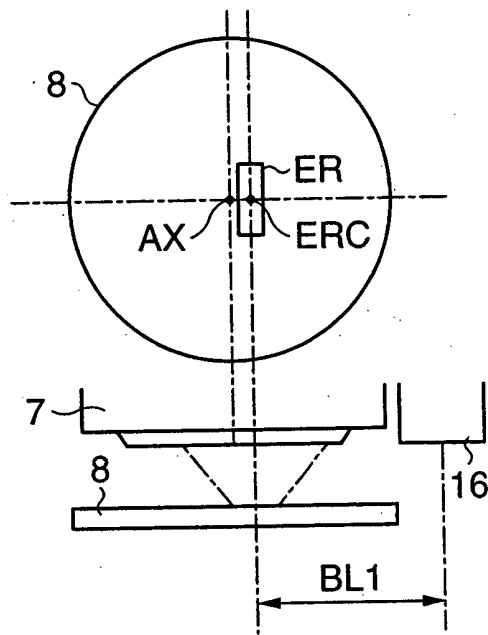


FIG. 2B

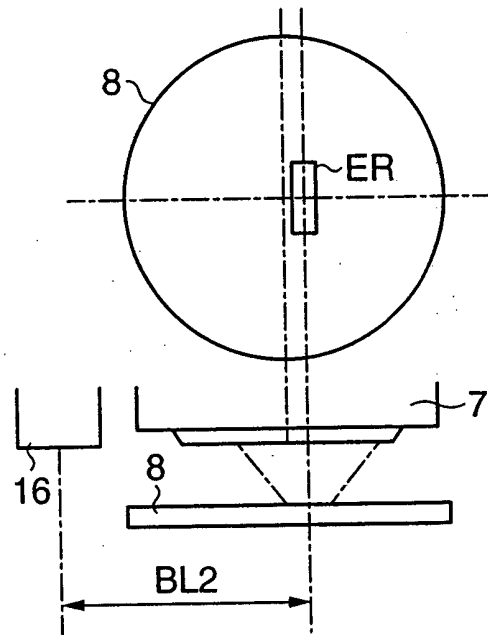
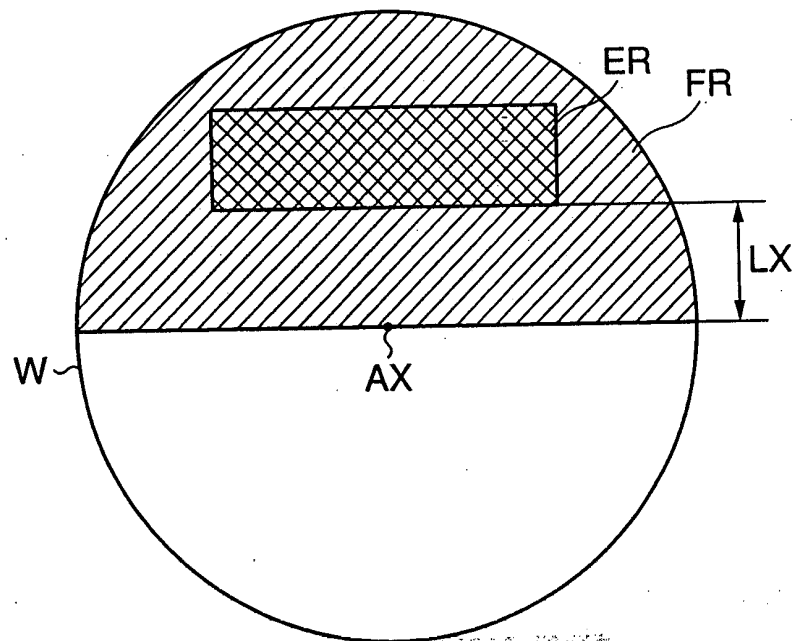


FIG. 2A

**FIG. 3**

*[Faint, illegible handwritten notes]*

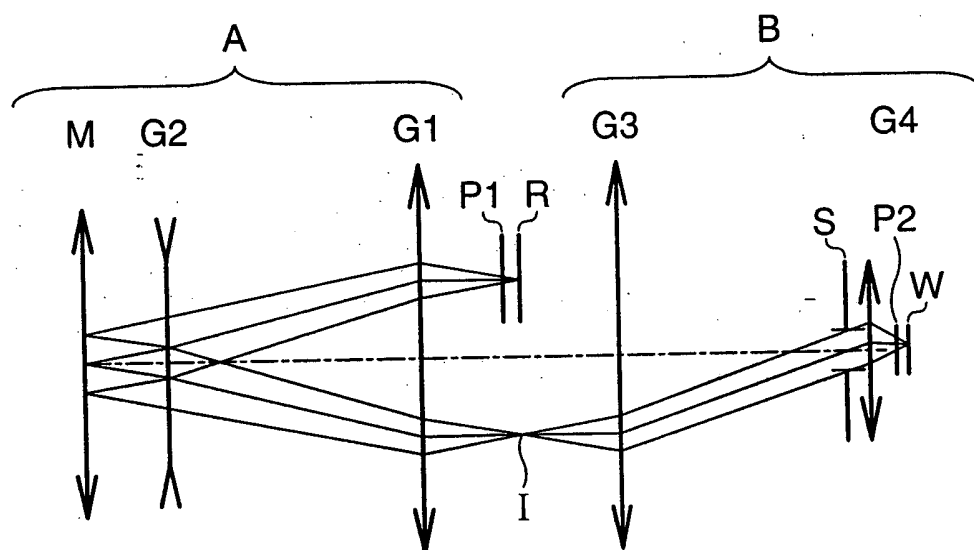
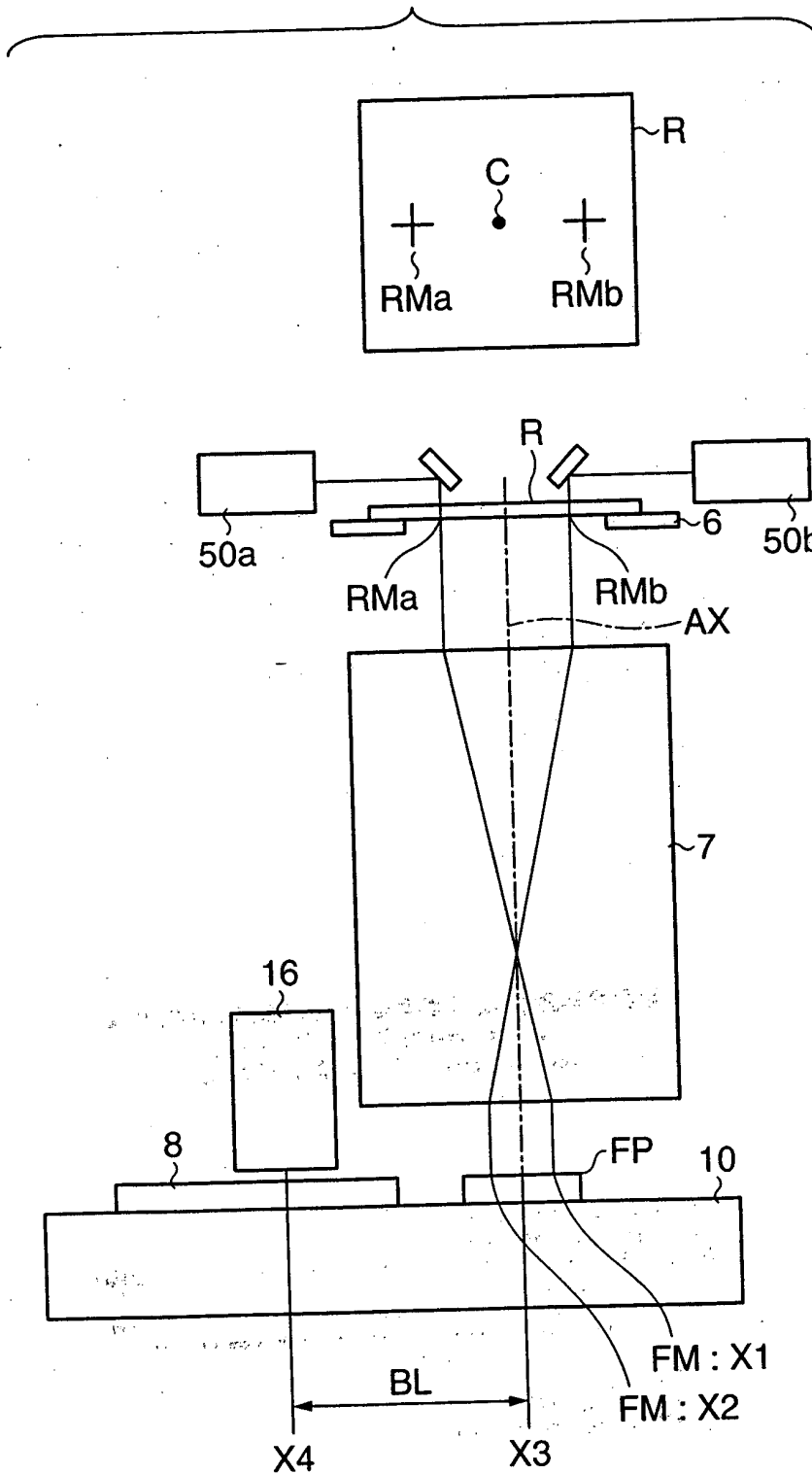


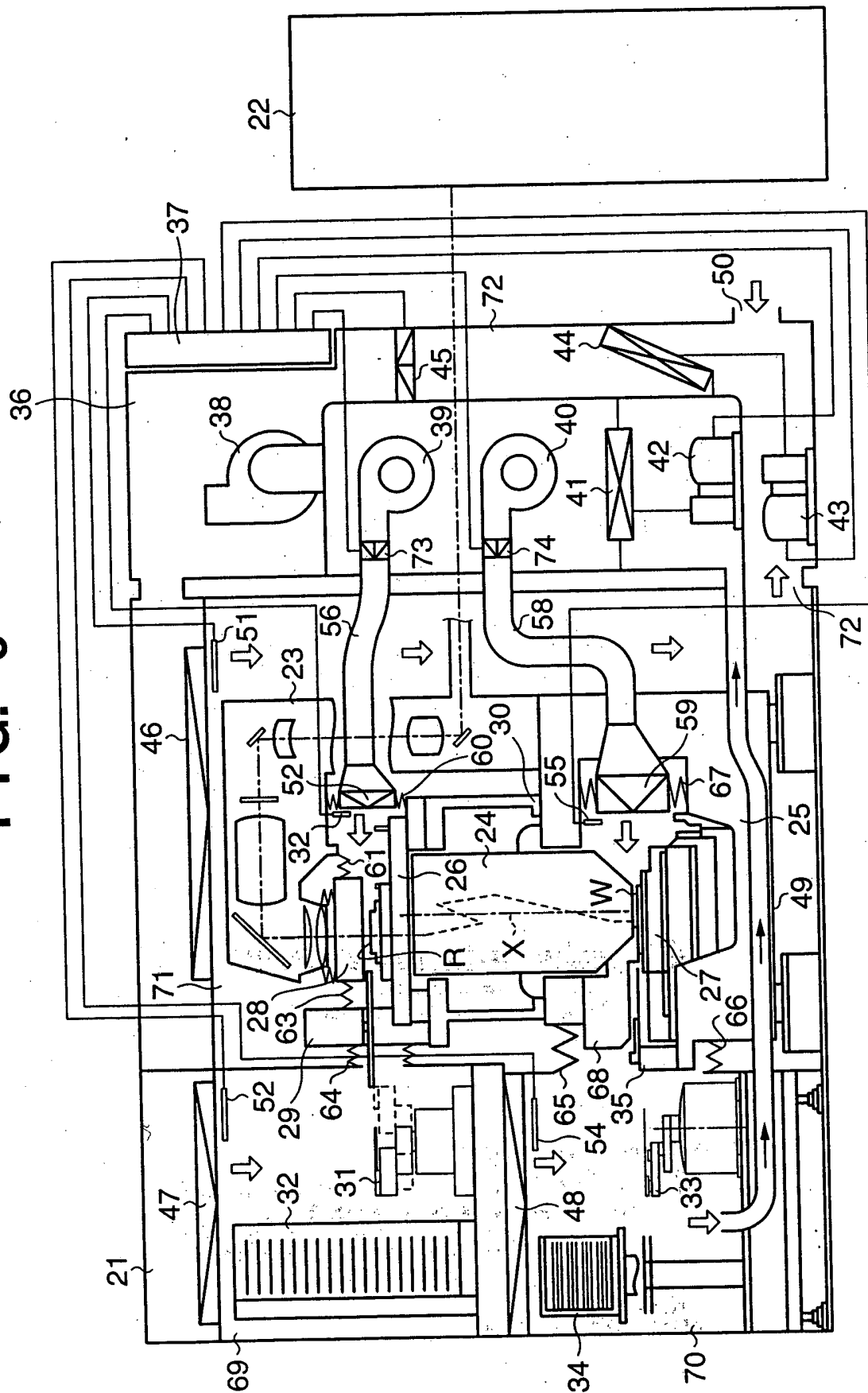
FIG. 5



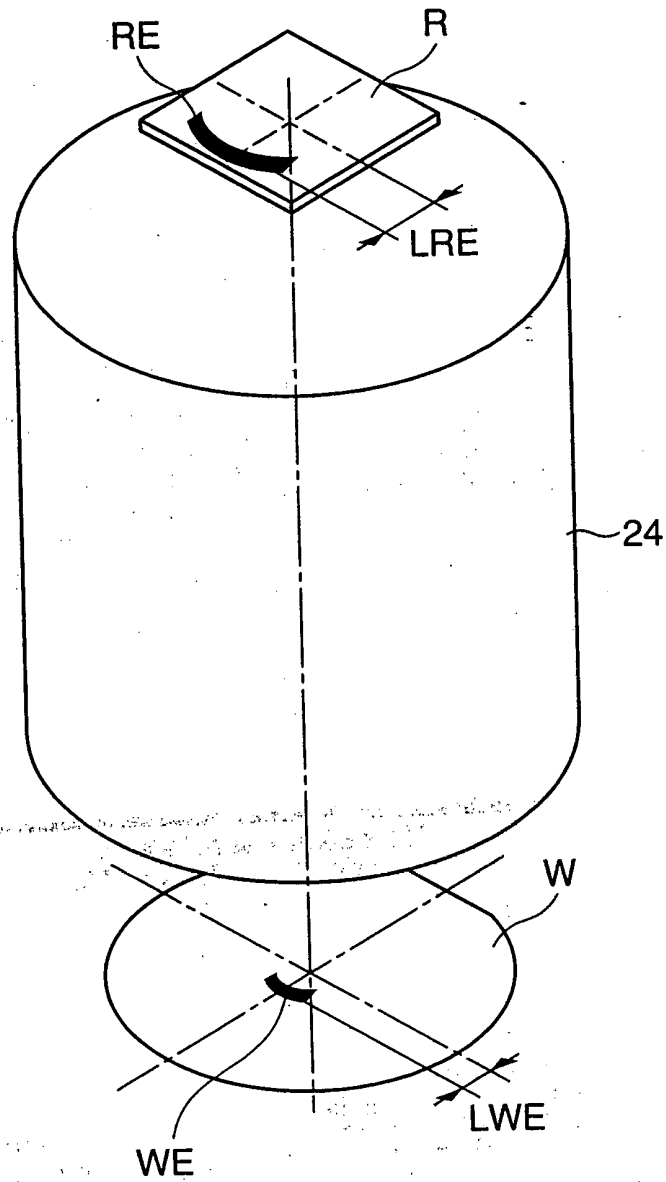
000000-11301

TOEFT-85698660

FIG. 6



[illegible]

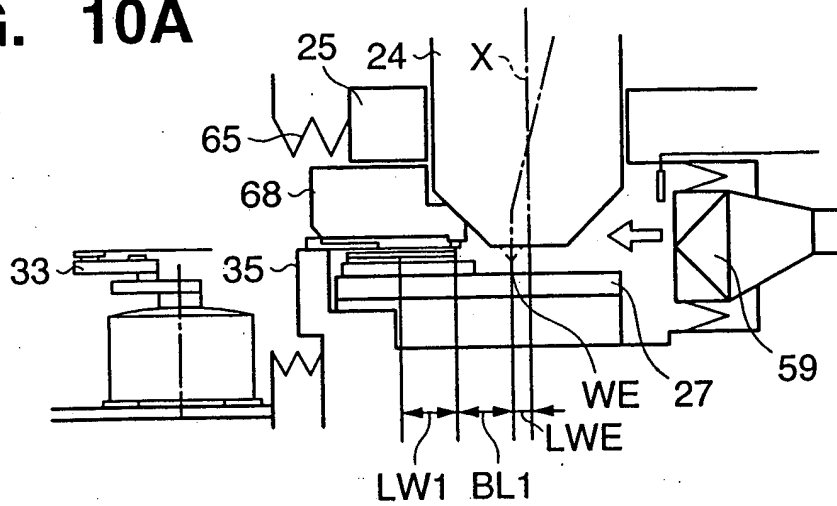
**FIG. 8**

00000000-111111

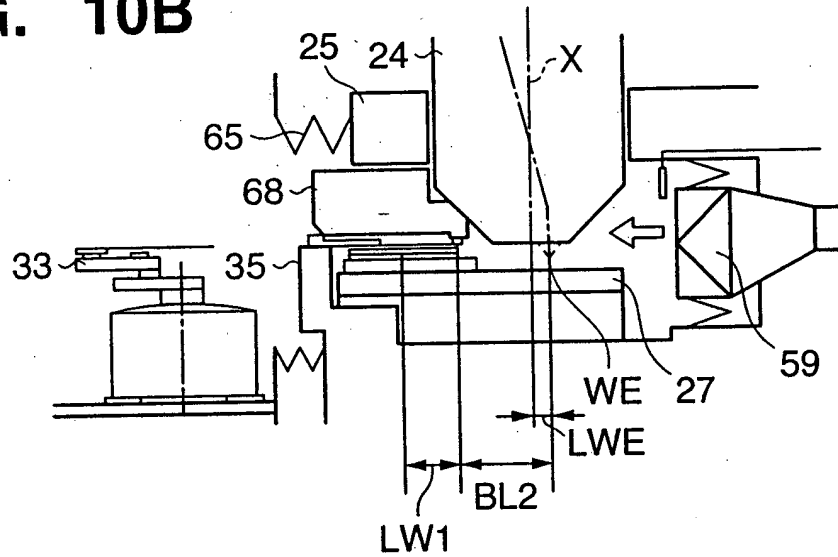




**FIG. 10A**



**FIG. 10B**



**FIG. 10C**

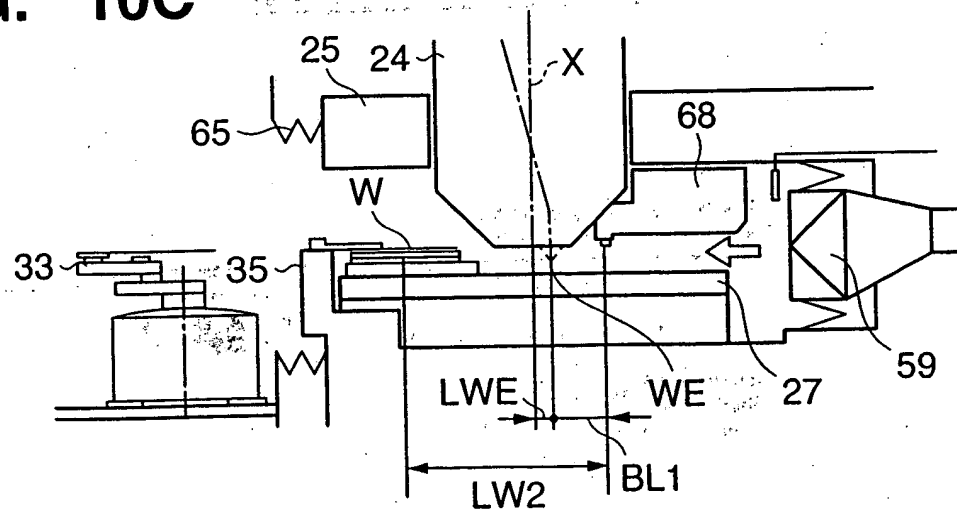


FIG. 10A

FIG. 11

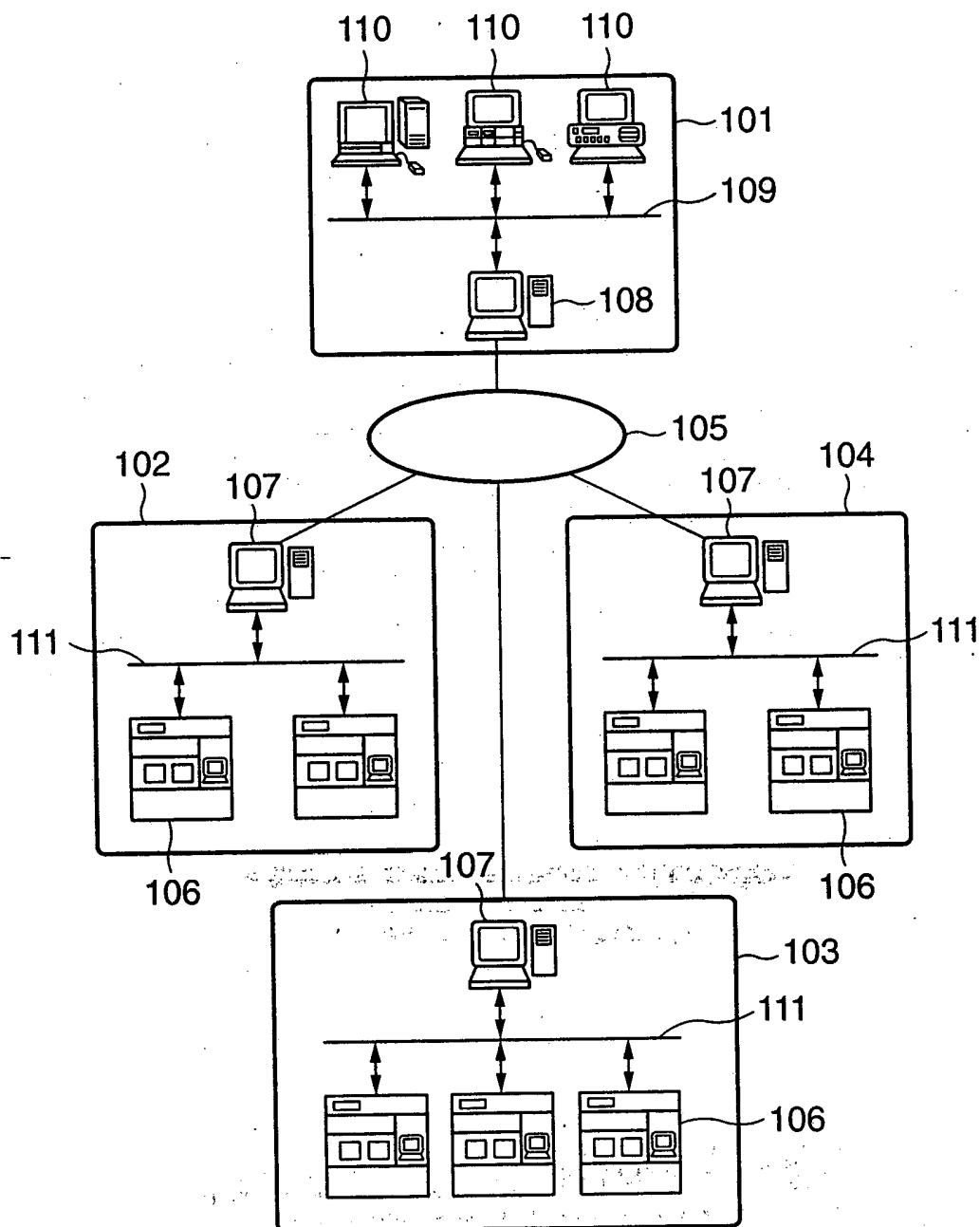


FIG. 12

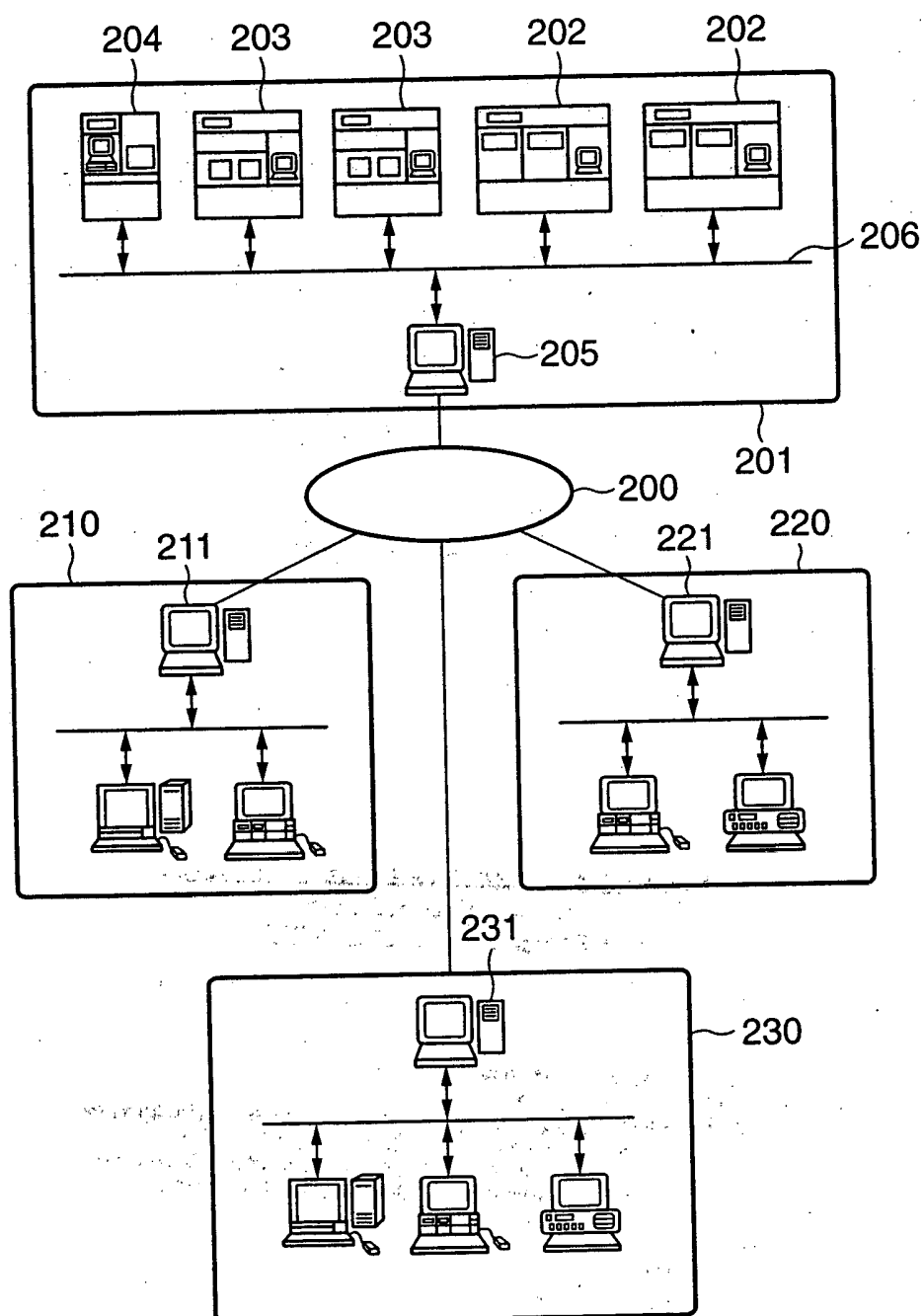


FIG. 13

URL

MALFUNCTION DATABASE INPUT SCREEN

DATE OF OCCURRENCE  ~ 404

MODEL  ~ 401

SUBJECT MATTER  ~ 403

EQUIPMENT SERIAL NO.  ~ 402

DEGREE OF URGENCY  ~ 405

CONDITION  ~ 406

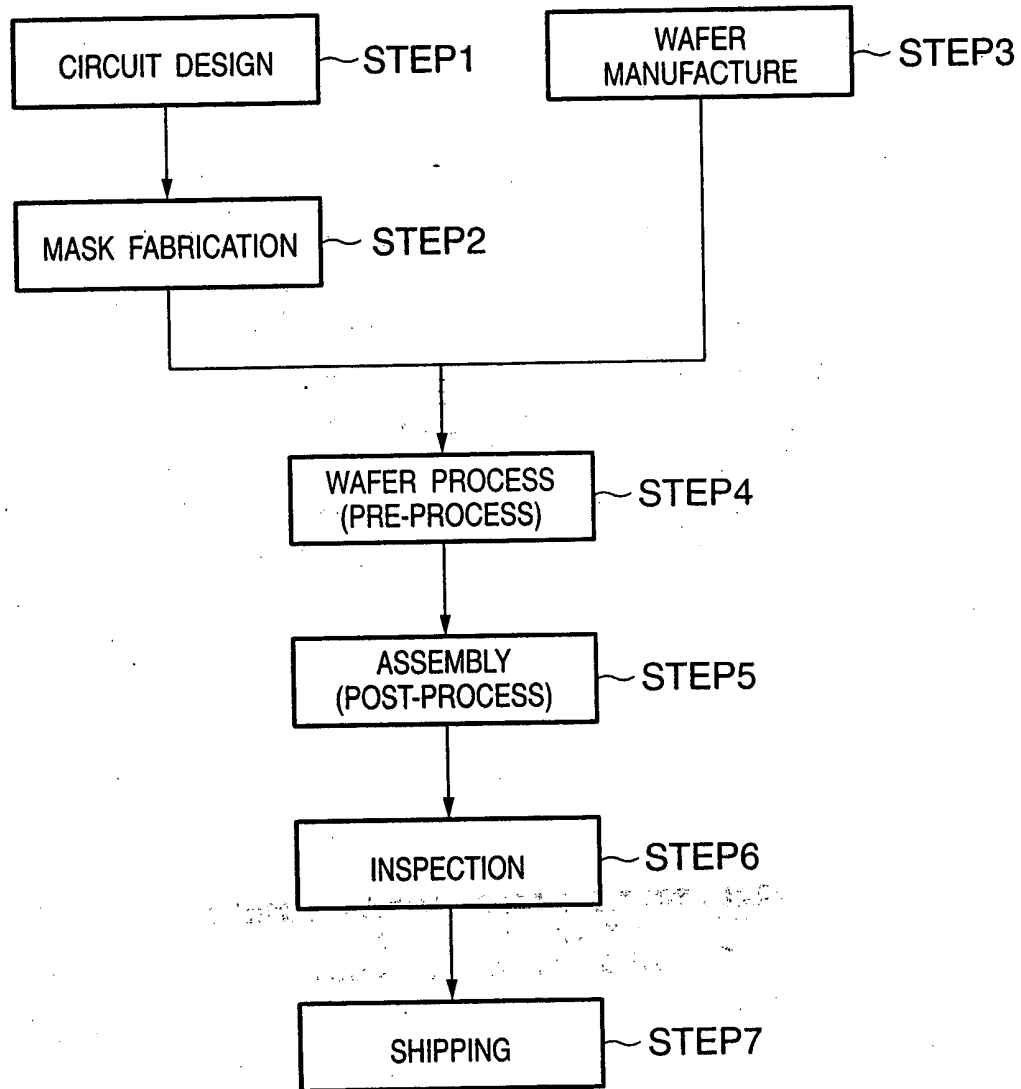
COUNTERMEASURE METHOD  ~ 407

PROGRESS REPORT  ~ 408

410 411 412

[LINK TO DATABASE OF RESULTS](#) [SOFTWARE LIBRARY](#) [OPERATION GUIDE](#)

FIG. 14



FLOW OF SEMICONDUCTOR DEVICE MANUFACTURE

## WAFER PROCESS

